

A Novel Micromachined Flow Sensor Using Periodic Flapping Motion of a Planar Jet Impinging on a V-shaped Plate

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Outline

- **Introduction**
- **Design and fabrication of micro flow sensors**
- **Experimental data**
- **Conclusions**

Introduction

• Impinging jet column appears to flap in a periodical motion with time.

Strouhal number

$$S_t = \frac{f_F L}{U_j} = \text{const}$$

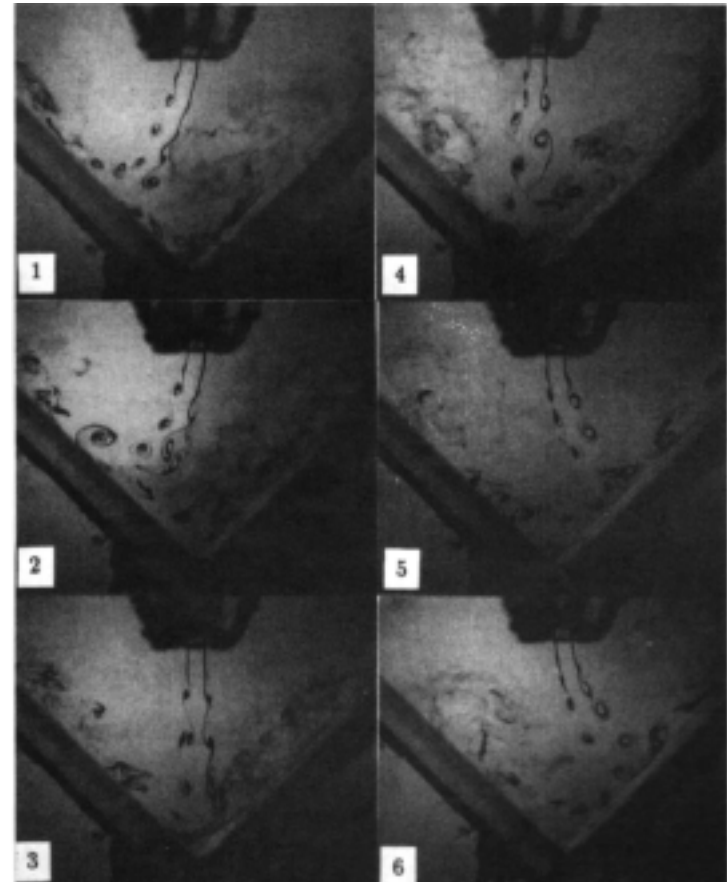
Frequency --> velocity

f_F : flapping frequency

U_j : flow velocity

L: distance from apex of V-shaped plate to nozzle exit

Water channel experiment



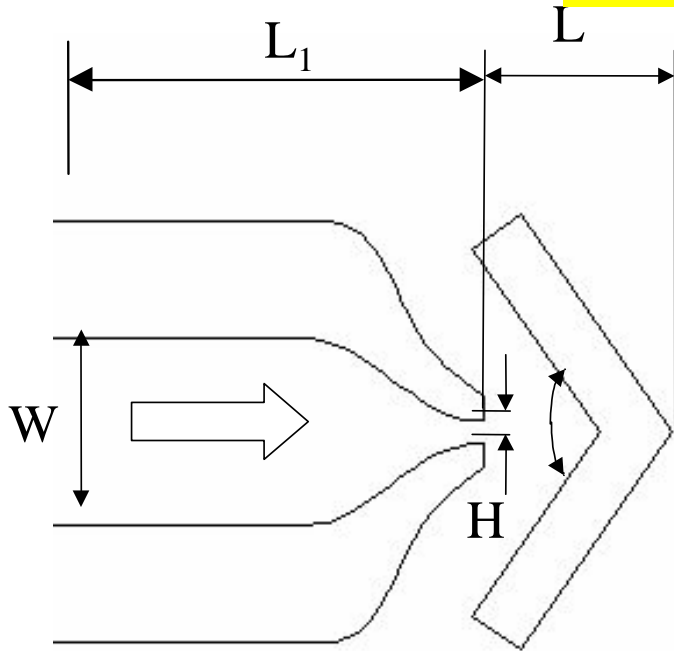
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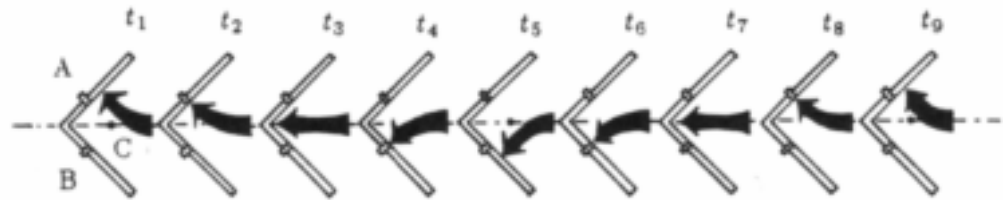
Motivation

- Most micro flow sensors encounter a serious problem while measuring extremely small volumes of flows since low signal to noise ratio is inherent while measuring DC current or voltage.
- The present study is therefore aimed to demonstrate a novel micromachined flow sensor capable of detecting extremely small amounts of volumetric flow rate (down to 2 nl/s) and extra-low fluid flow velocity (0.15 mm/s).
- The innovative flow sensor detects a **periodic flapping motion of a planar jet impinging on a V-shaped plate**. Instead of detecting DC current or voltage signals induced by small volumes of flow, the micro flow sensor detects the **oscillating frequency of the periodic flapping jet**, resulting in a higher sensitivity and a larger dynamic range than existing products.

Sensor design



- Planar micro chamber integrated with built-in sensors
- Flapping frequency detected by sensors

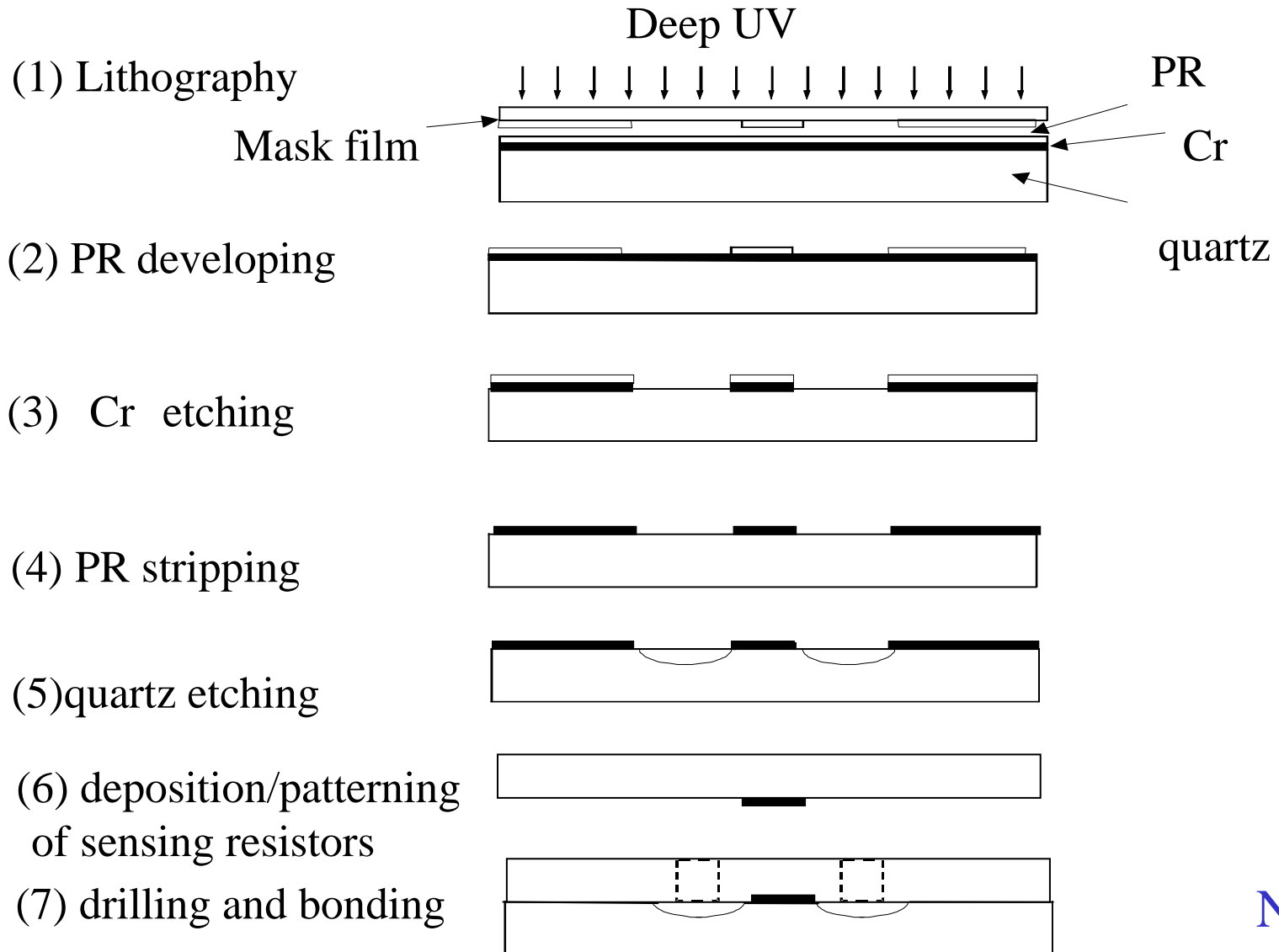


Sensors	W (μm)	H (μm)	L (μm)	L/H	θ ($^\circ$)
1	2250	360	2790	7.75	70
2	2250	360	1440	4	110

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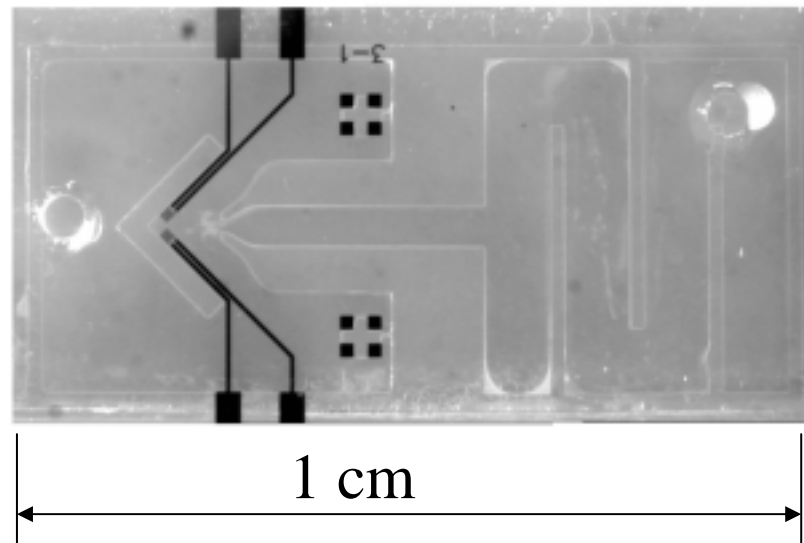
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Fabrication Process

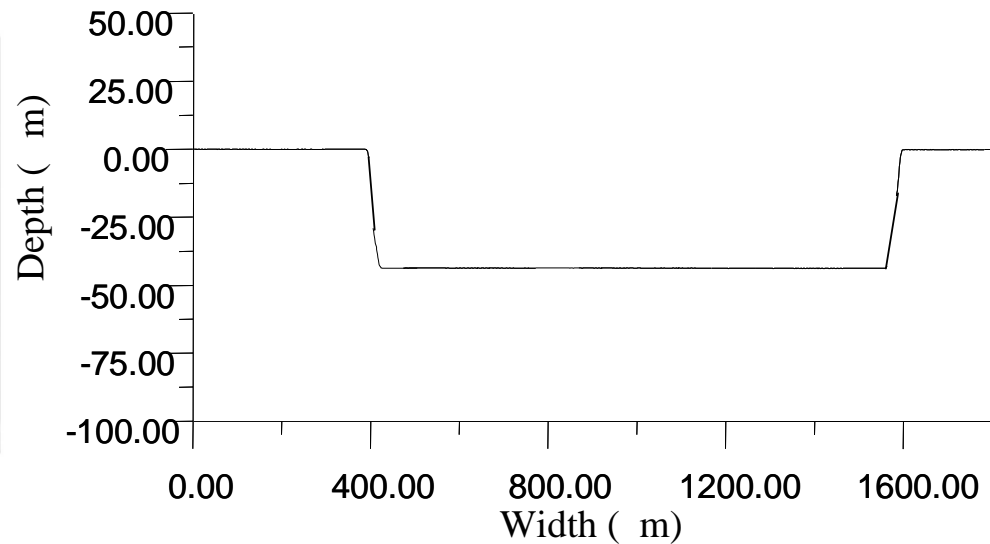


Micro flow sensor

Picture



Surface profile

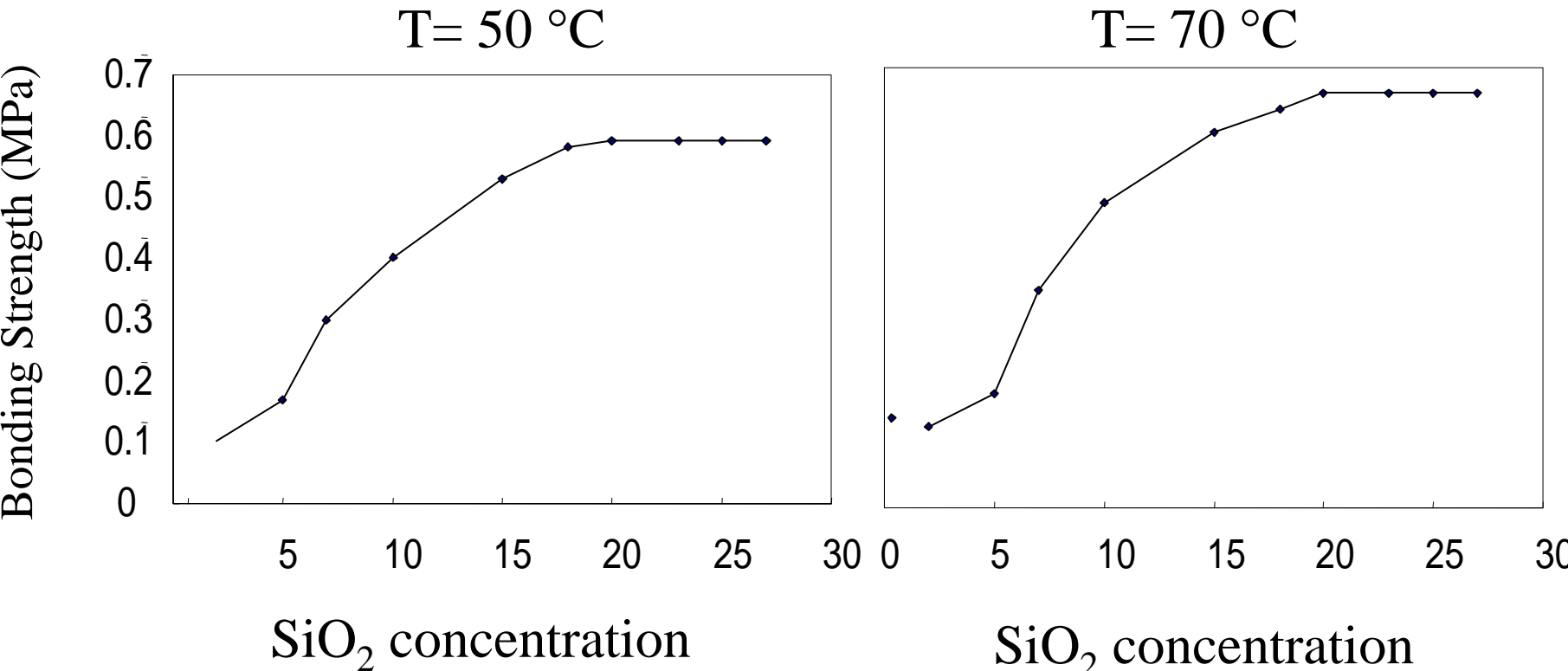


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Bonding Strength

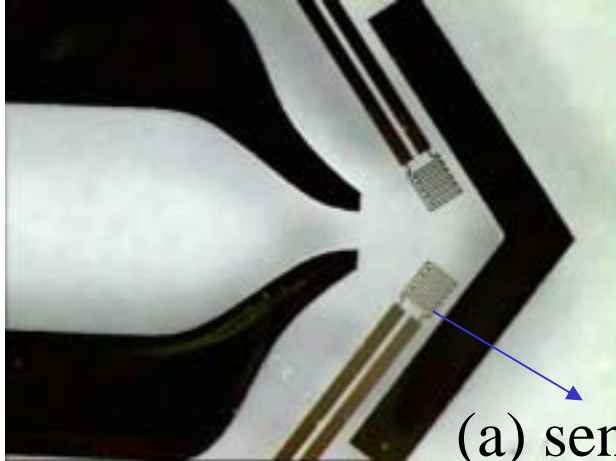
- Low-temperature bonding technique for quartz substrates
- Sodium silicate solution ($\text{SiO}_2\text{:NaOH}$) spin-coated on the surface
- Heated for at least 8 hours.



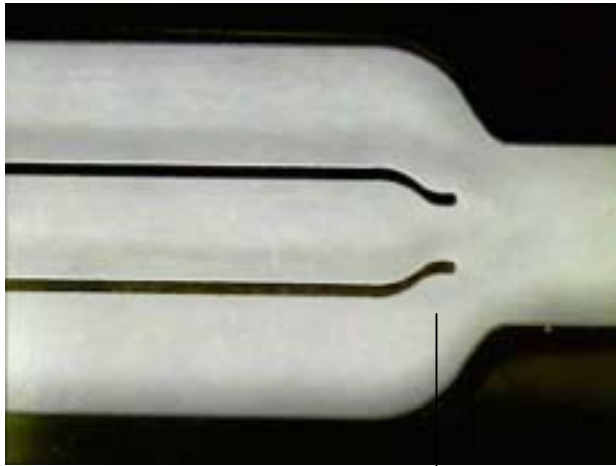
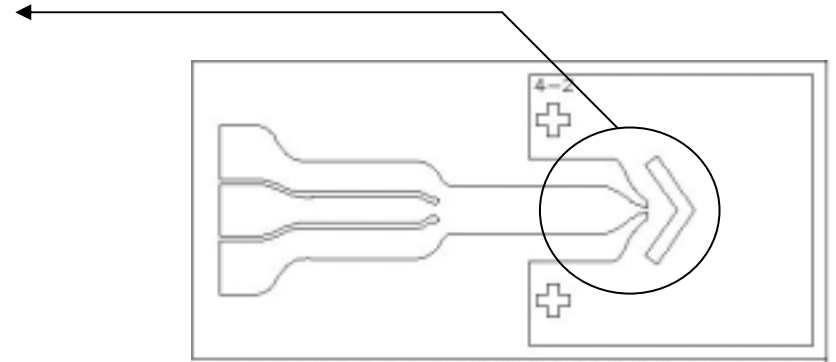
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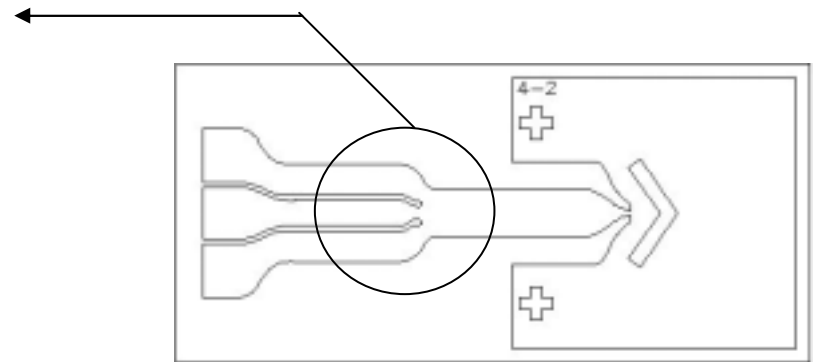
Close-up picture of the sensor



(a) sensing resistors



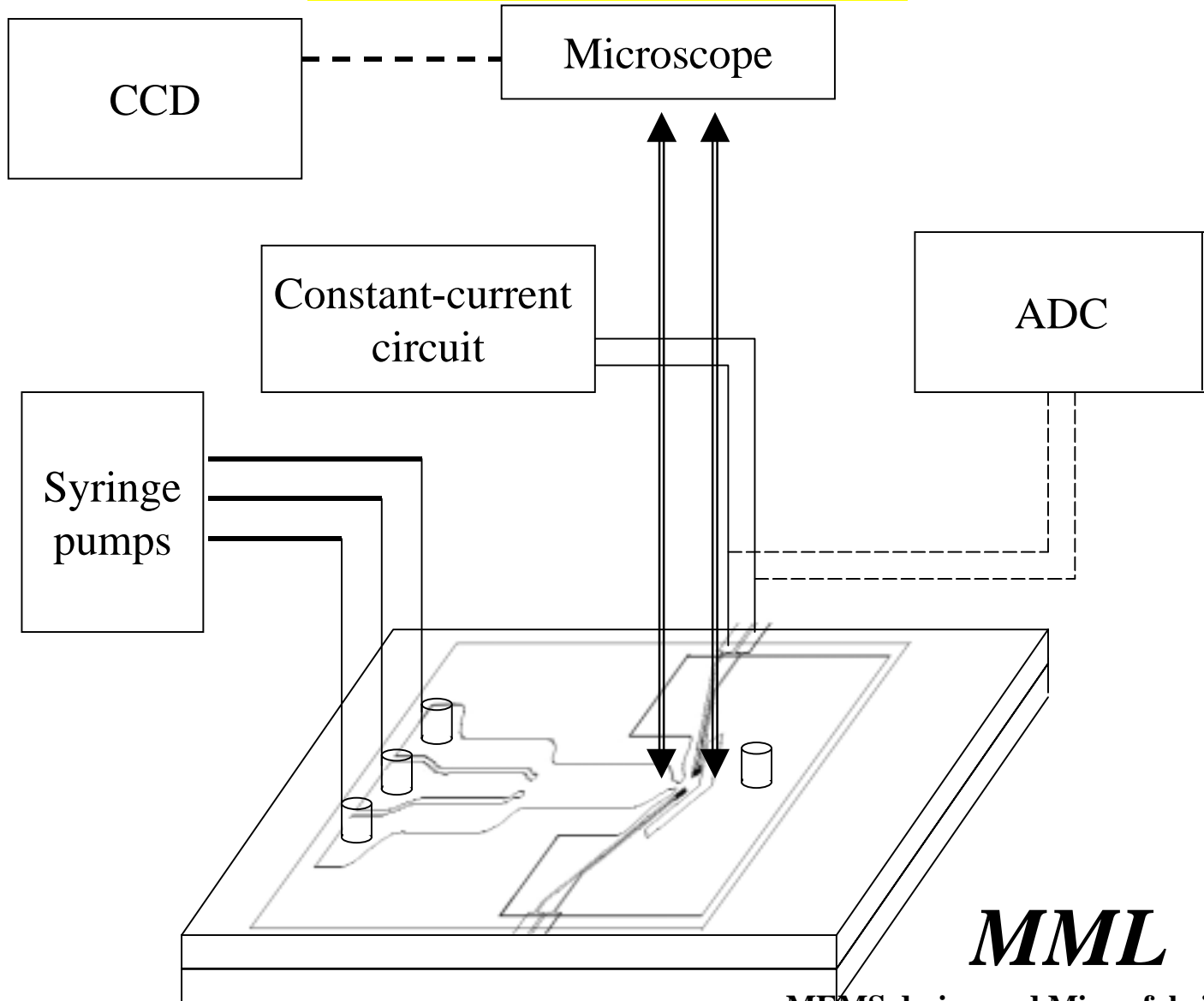
(b) convergent nozzles



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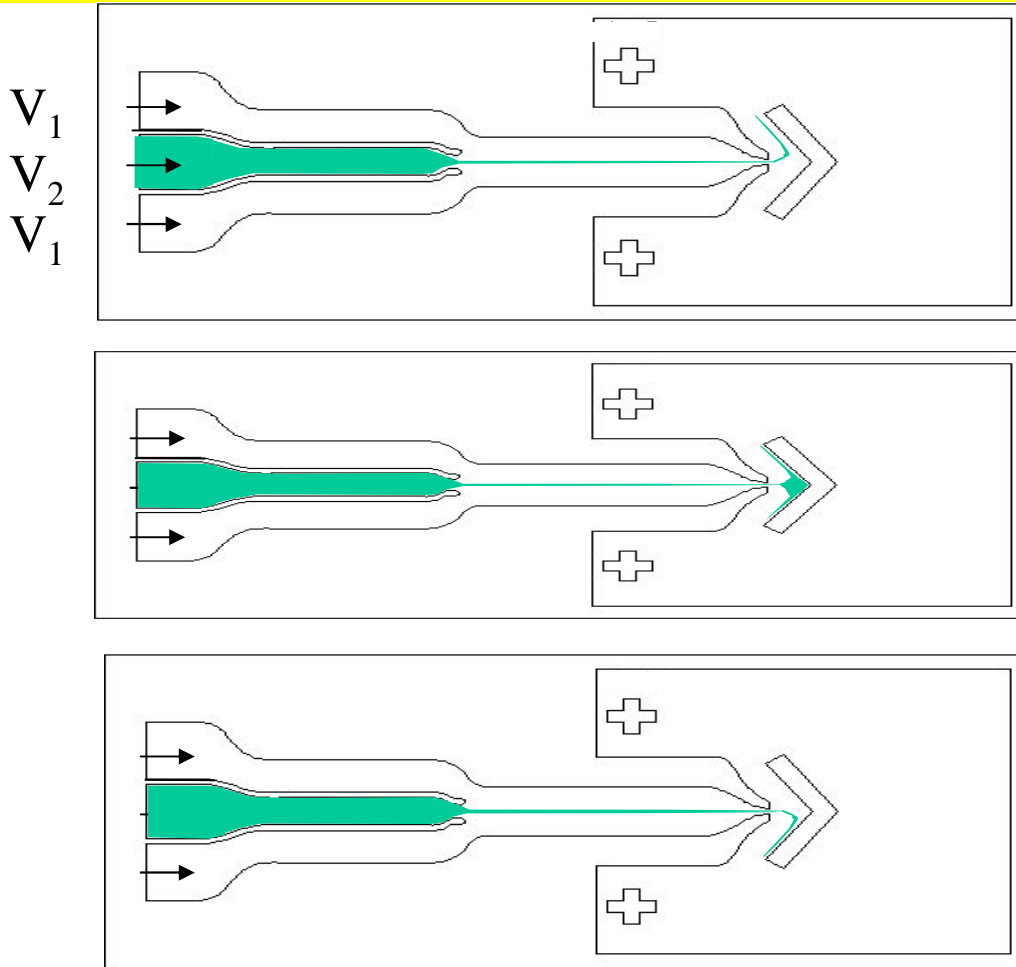
Experimental setup



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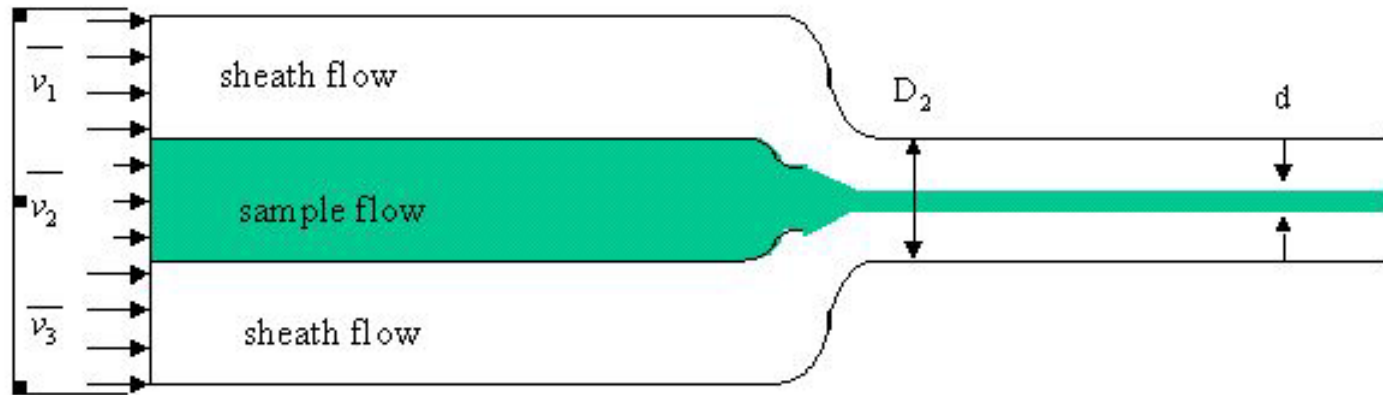
Schematic representation of typical oscillograms of the jet-column flapping motion



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Hydrodynamic focusing inside a flow cytometer



- Center sample stream constrained by two surrounding sheath flows.
- Focused width can be predicted by the following formula.

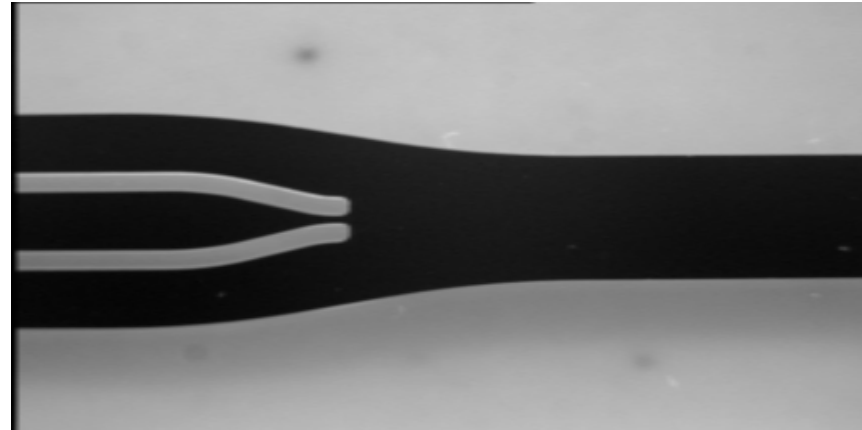
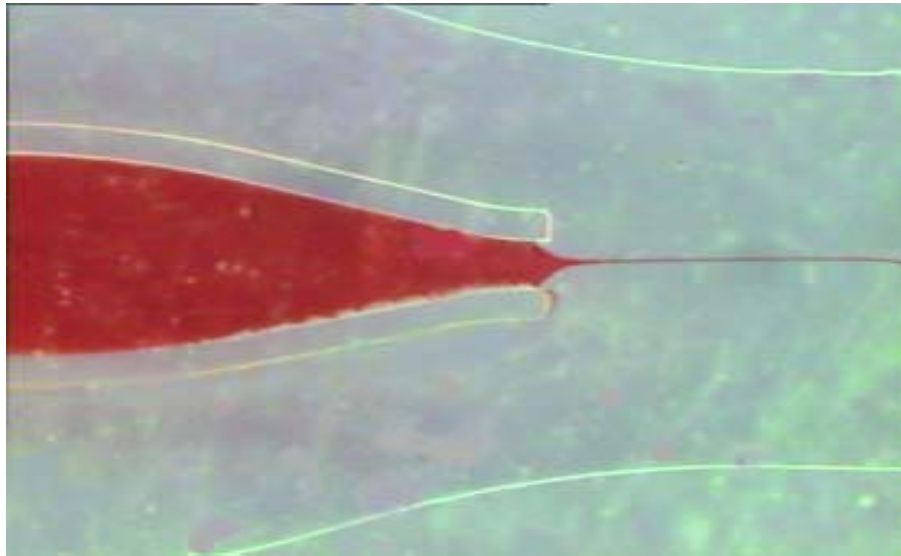
$$d = \frac{\rho_a D_a}{1.5 \left(\rho_1 \frac{v_1}{v_2} \frac{D_1}{D_2} + \rho_2 + \rho_3 \frac{v_3}{v_2} \frac{D_{31}}{D_2} \right)} \quad (\text{Lee et al. 2001, ASME})$$

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Hydrodynamic focusing

Micro chip



- the size of focused sample stream can be reduced to about $3\ \mu\text{m}$

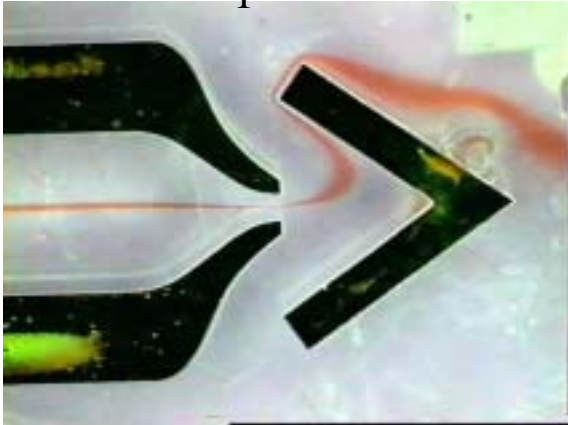
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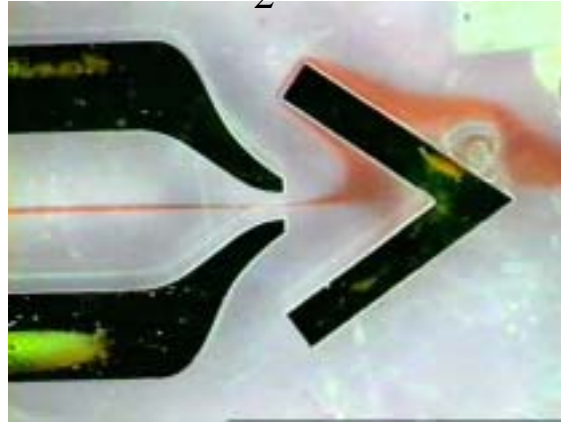
Flapping motion of an impinging jet

Sensor #1

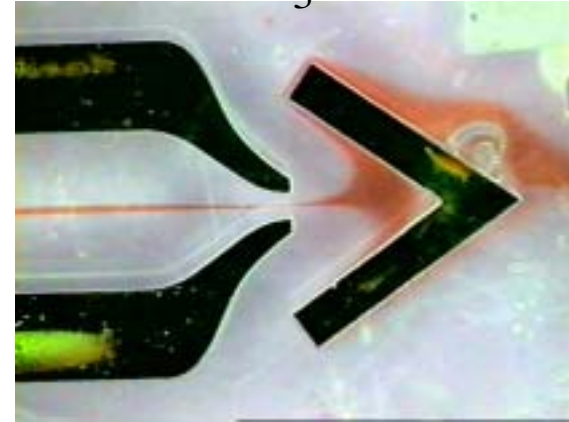
t_1



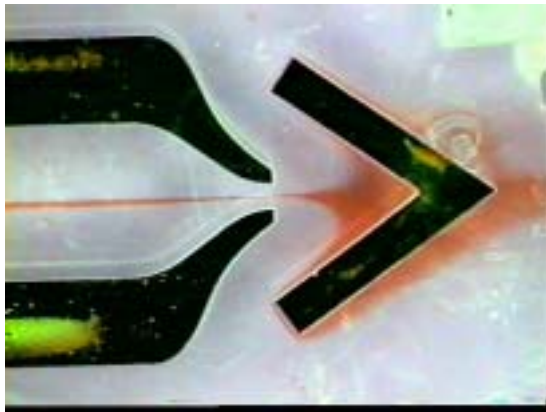
t_2



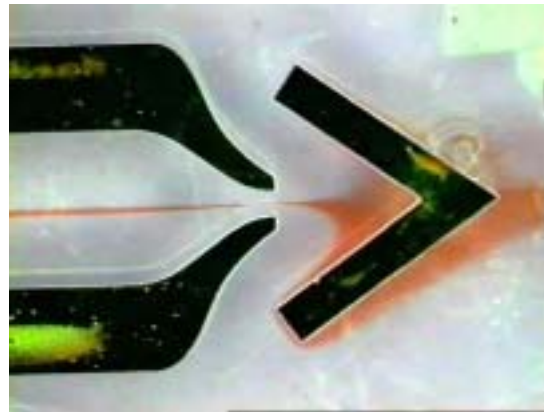
t_3



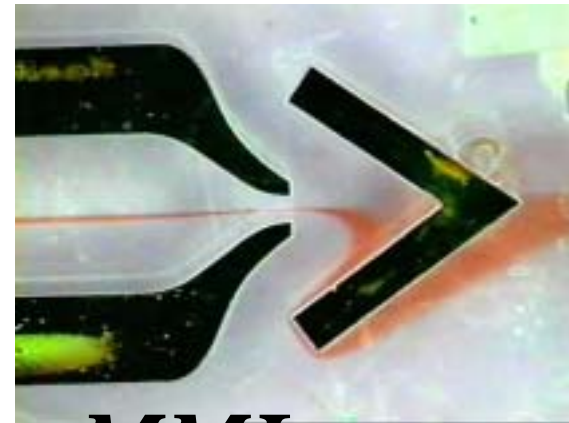
t_4



t_5



t_6

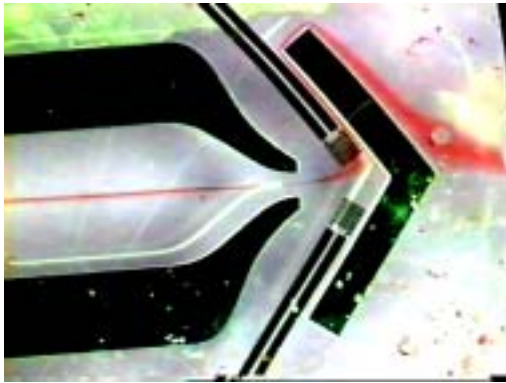


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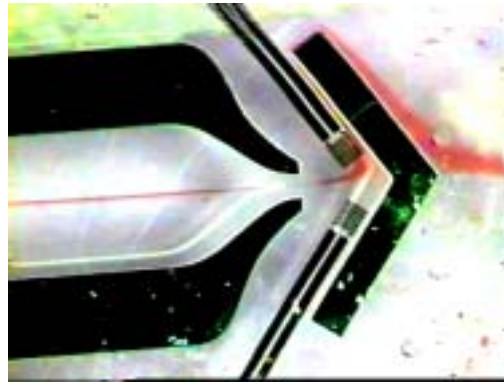
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Flapping motion of an impinging jet

Sensor #2



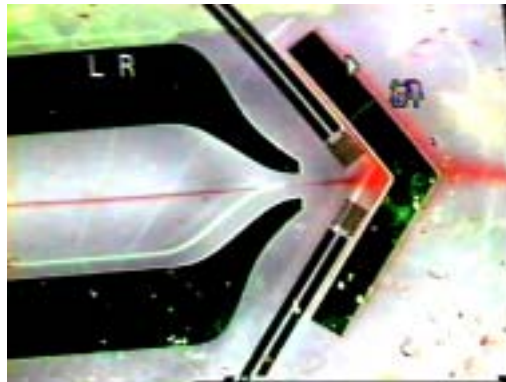
t1



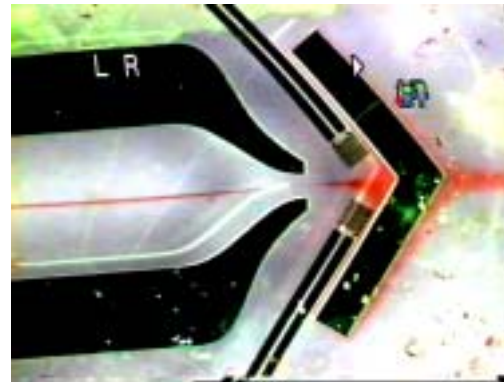
t2



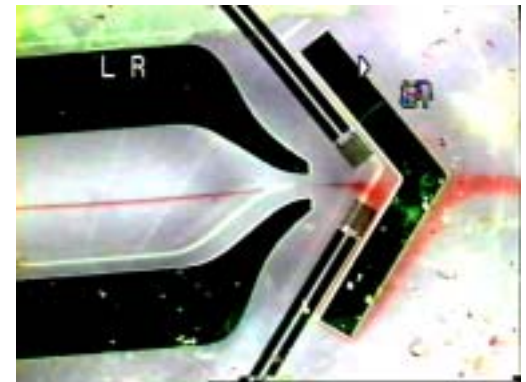
t3



t4



t5

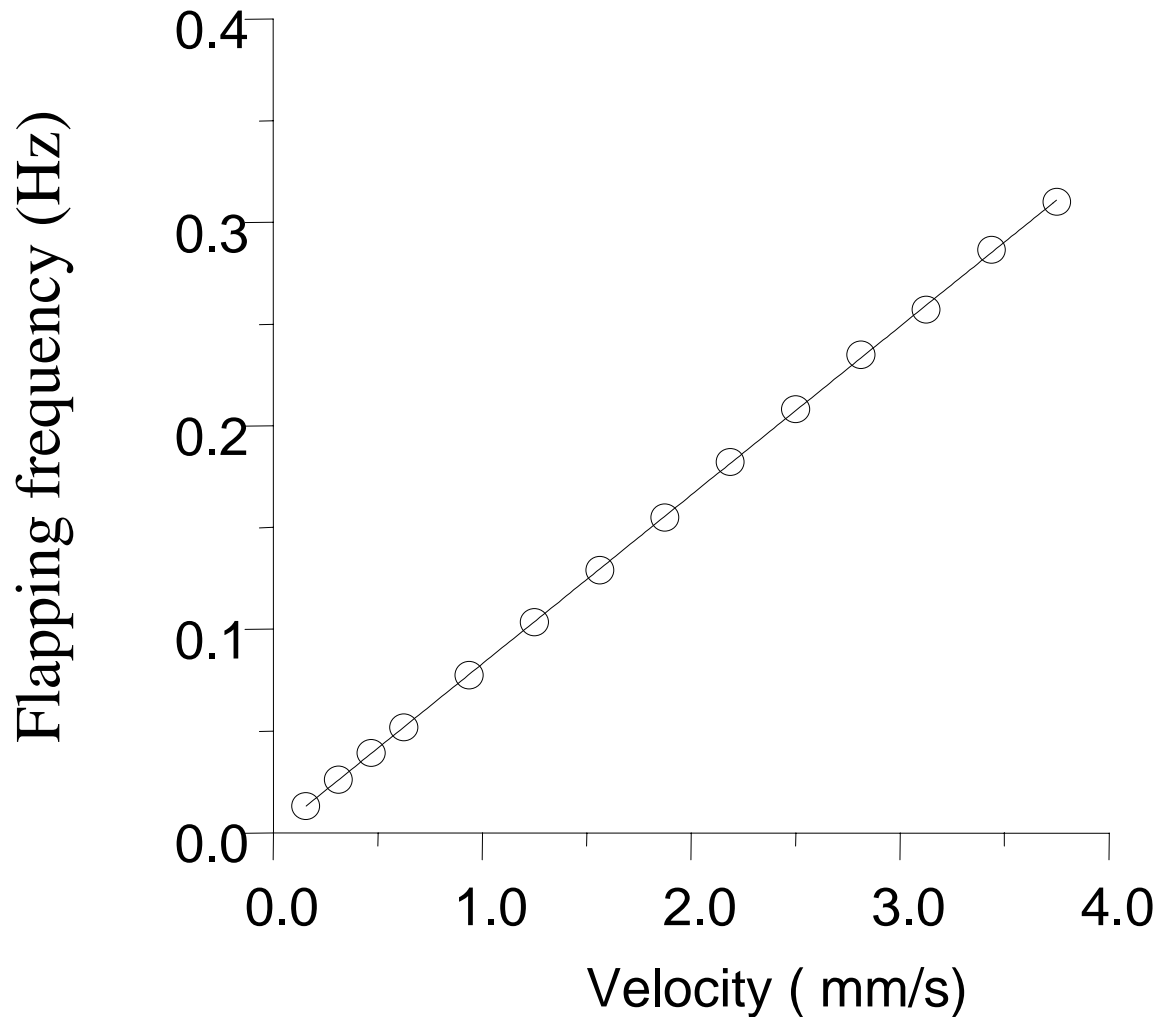


t6

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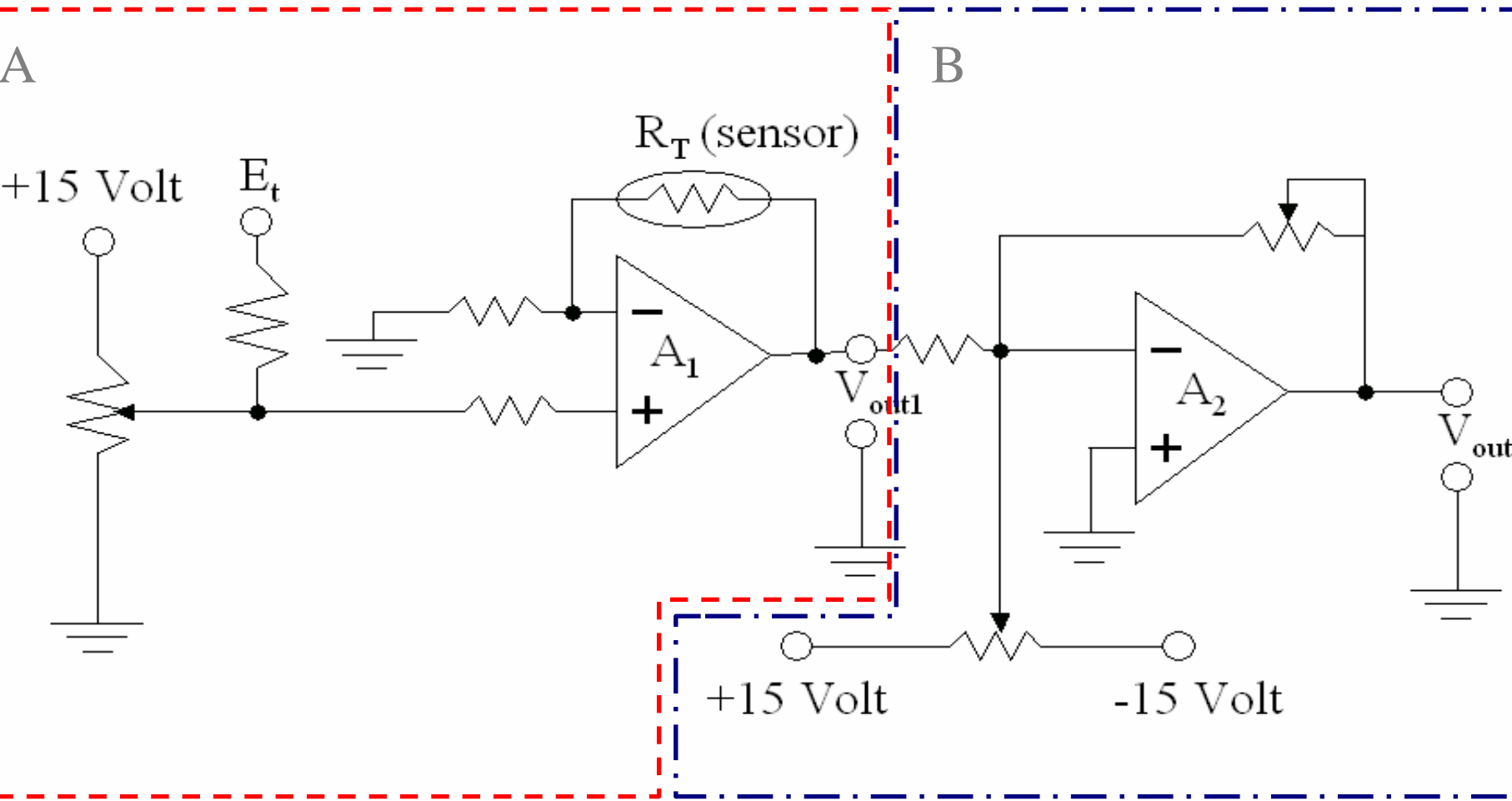
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Experimental Data

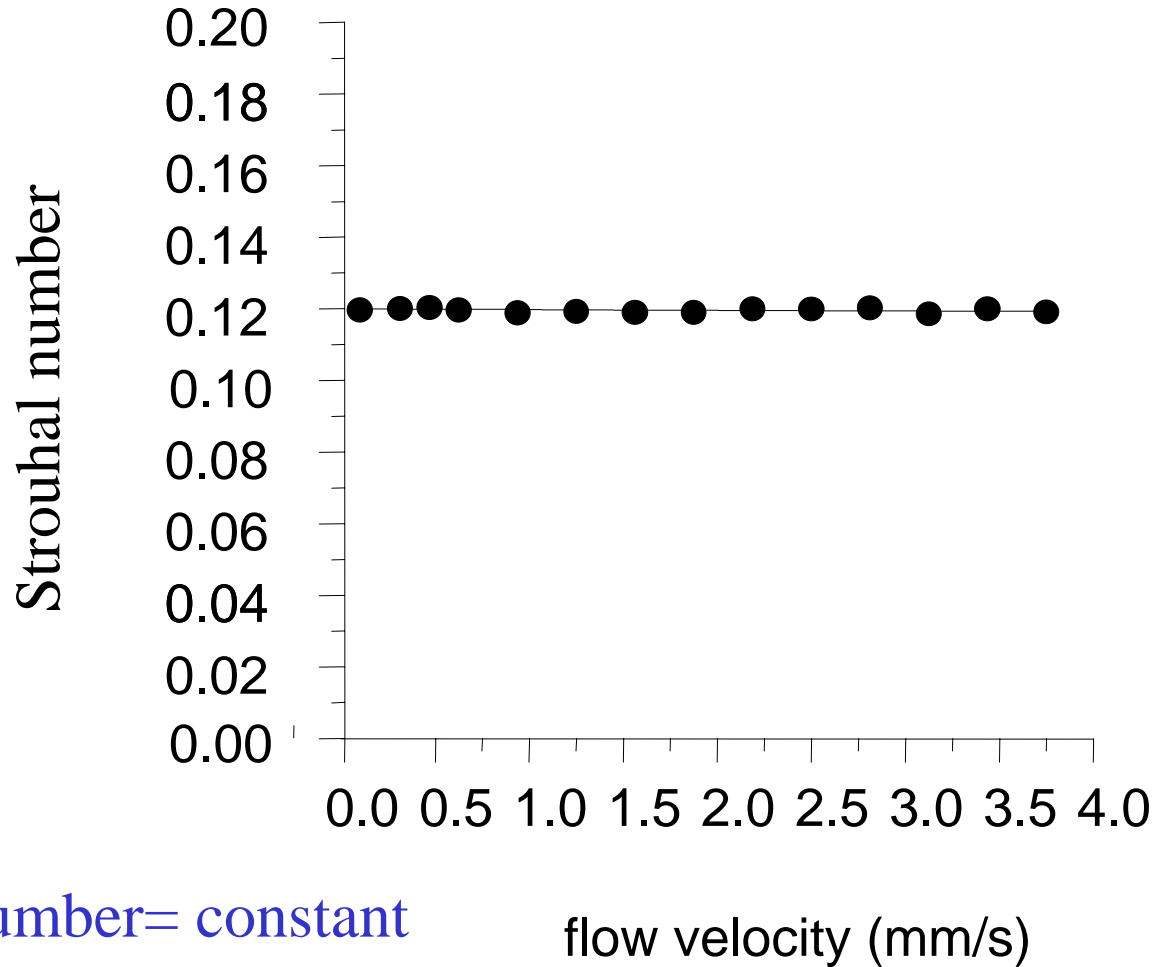


- Frequency is linearly proportional to velocity **MML** NCKU

Constant-current Driving Current



Velocity vs. Strouhal number



Strouhal number= constant

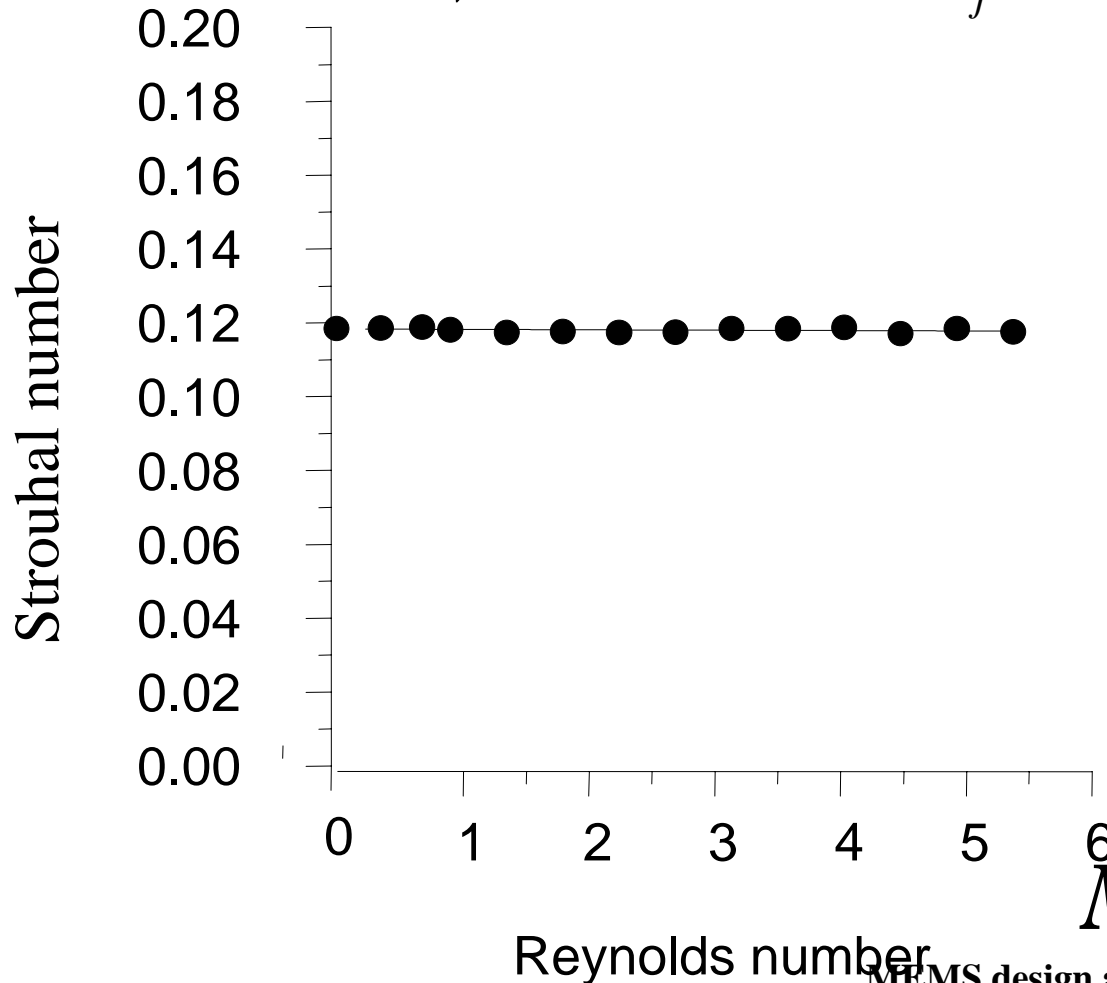
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Reynolds number vs. Strouhal number

$$\text{Re} = \frac{U_j L}{\nu}$$

$$S_t = \frac{f_F L}{U_j}$$



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Conclusions

- ❑ Flapping motion of an planar jet impinging on a V-shaped plate, was used for flow sensing.
- ❑ A pair of sensing resistors were integrated with a convergent nozzle and a V-shaped plate downstream.
- ❑ Two methods were used to verified the performance of the sensor.
 - (a) Flow visualization
 - (b) Electronic sensing
- ❑ Flow velocity is still linearly proportional to the frequency of the jet flapping motion in microfluidic device.
- ❑ It is the first time that low-Reynolds-number flow is reported with a flapping motion for flow impinging on a V-shaped plate.